


APPLICATION DATA SHEET

Electronic Version v14

Stylesheet Version v14.0

Title of Invention	[ION SAMPLING SYSTEM FOR WAFER AND SAMPLING METHOD THEREOF]		
Application Type : regular, utility Attorney Docket Number : 10573-US-PA			
Correspondence address: Customer Number: 31561 			
Priority Data: Doc.No: 92107254; Country -TW ; Date: 2003-03-31 us-priority-claimed			
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